

Figure 3.1: a) The general planar circuitry design used for characterizing coupling efficiency and b) an individual device.

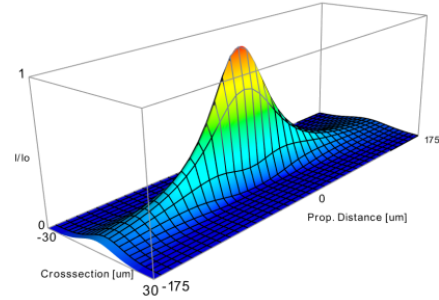


Figure 7: Regularly-spaced elevation plot of crosssections of the **WPM** simulation results of a Gaussian input. Height and color both resemble intensity for better visualisation.

through an overlap integral. The Gaussian overlap integral  $G_{AB}$  of an array  $A$  and its corresponding best-fit array  $B$  over the volume  $V$  is calculated by

$$G_{AB} = \frac{|\int A \cdot B \, dV|^2}{\int |A|^2 \cdot |B|^2 \, dV}. \quad (3.3)$$

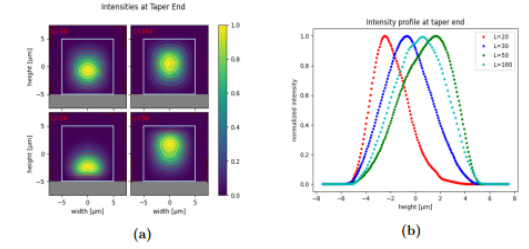


Figure 6: Meep simulations of tapers with lengths of  $L = 20 \mu\text{m}$ ,  $L = 30 \mu\text{m}$ ,  $L = 50 \mu\text{m}$  and  $L = 160 \mu\text{m}$ . In (a) the normalised intensity at the end of the tapers is plotted. The light blue frame is a reference to indicate the tapers boundaries and the grey areas resemble the substrate. Added is a differently coloured contour plot to further enhance the visualisation of the modes geometry. In (b) the central vertical profiles of the different distributions are plotted.

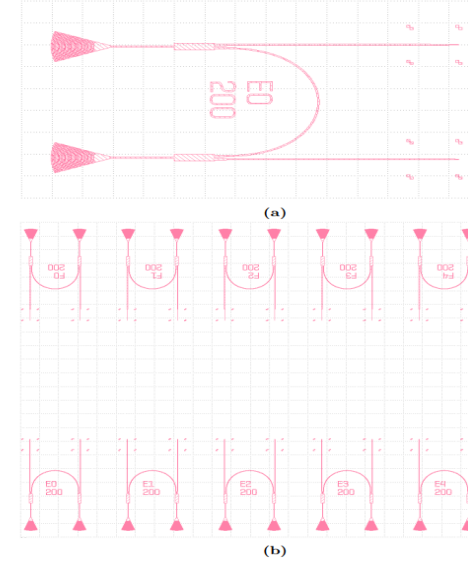


Figure 17: Design of the nanophotonic structures. One unit contains two grating couplers, each leading to a **MMI** where the inner arm of the two connects the two, leading half of the light back to the other grating coupler, while the other arm connects to a taper (a). This taper is the port for the direct-laser-writing components that are printed in a later step. These units are arranged in rows with opposing directions (b). After fabrication it is possible to cut the chip in the gap between the two rows to create a clean edge at a desired distance from the port.